MEMS Based Pressure Sensors

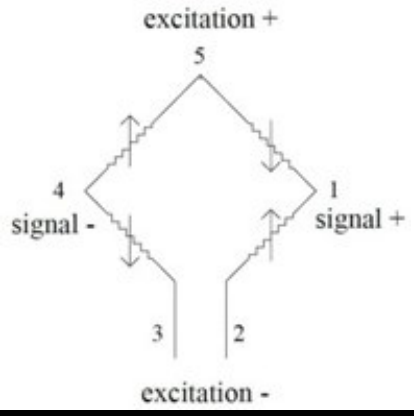
PRODUCT DESCRIPTION:

SCL is involved in developing MEMS based pressure sensors. Sensors are in the form of Bridge of four piezo-resistors to give differential output proportional to applied pressure. The absolute sensors have an internal vacuum reference.

These are intended for use with Non-corrosive, Non-ionic working fluids; such as air and dry gases.

FEATURES:

- Operating Ranges : Upto 30 bar
- Package : TO8, Chip on Board
- Custom Package option available
- Sensor dies are available



Product Specifications			
S.No.	**Parameters**		**Specification**
1	Operating Pressure Ranges		Upto 30 bar
2	Pressure Reference		Absolute, Gauge, Differential
3	Proof Pressure		> 1.5 Times Operating Pressure
4	Burst Pressure		>3 Times Operating Pressure
5	Operating Temperature		-40ºC to 125ºC
6	Storage Temperature		-40ºC to 125ºC
7	Bridge Resistance (at 25°C)		2.5 KΩ ± 1 KΩ
8	Non-Linearity		<0.2 % FSR
9	Hysteresis		<0.1%FSR
10	Repeatability		<0.1%FSR
11	Bridge Voltage		3V (Typ.), 1V – 5V
12	Full Scale Range (FSR)		75 ± 25 mV (at 3Vexc)
13	Offset		±10 mV
14	TC of Bridge Resistance (TCR)		1000±200 (ppm/ºC)
15	TC of Span (TCS)	Voltage Excitation	-2000±500 (ppm/ºC)
		Current Excitation	-1000±500 (ppm/ºC)
16	TC of Offset (TCO)		±30 uV/ºC
17	Response Time		< 5ms